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INFORMATION DISCLOSURE
STATEMENT BY APPLICANT*filed after final rejection*

APPLICATION NO.: 09/361,700

ATTY. DOCKET NO.: S01022.80201.US

FILING DATE: July 27, 1999

CONFIRMATION NO.: 5850

APPLICANT: Pierrick Descure

GROUP ART UNIT: 2811

EXAMINER: Gene M. Munson.

Sheet 1 of 2

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Examiner's Initials	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YYYY
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EXAMINER

G. MUNSON

DATE CONSIDERED

19 MAY 2005

#EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.